



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**In the Application of:** NG et al.**Application Serial No:** 10/510,640**Filing Date:** December 2, 2004**Title:** Method of Etching a Semiconductor Device**Group Art Unit:** 2818**Examiner:** DANG, P.**Confirmation:** 1877

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

**RESPONSE TO OFFICE ACTION**

Dear Sir:

In response to the Office Action mailed April 25, 2006, please amend the above-identified application as indicated below.

Amendments to the Claims are reflected in the listing of claims which begins on Page 2 of this paper.

Remarks begin on page 5 of this paper.